

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: James Chingwei Li, et al

Serial No.

Filed:

Title: TESTING APPARATUS AND METHOD FOR DETERMINING AN ETCH BIAS ASSOCIATED WITH A SEMICONDUCTOR PROCESSING STEP

Mail Stop Non Fee IDS
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97(b)

Sir:

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicants bring to the attention of the Examiner the documents listed on the attached Form PTO-1449. This Information Disclosure Statement is being filed within three months of the filing of the above referenced application or before the mailing date of a first Office Action on the merits for the above-referenced application.

Copies of the listed documents are attached.

Applicants respectfully request that the Examiner consider the listed documents and evidence that consideration of relevant portions thereof by making appropriate notations on the attached form.

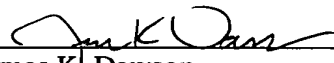
This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art". If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such documents.

Applicants further reserve the right to take appropriate action to establish the

patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

Respectfully submitted,

September 29, 2003


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FORM PTO-1449 (Modified) INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)	Docket No. 01SC062US2	Application Number
	Applicants: James Chingwei Li, et al	
	Filing Date	Group Art Unit

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number							Date	Name	Class	Subclass	Filing Date if Appropriate
	4	7	1	7	4	4	5	Jan.5,1988	Leung	156	626	

FOREIGN PATENT DOCUMENTS

	Document Number							Date	Country	Class	Subclass	Translation	
												Yes	No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	E. G. Colgan, R.J. Polastre, M. Takeichi and R.L. Wisnieff, <u>Thin-Film-Transistor Process-Characterization Test Structures</u> , February 12, 1998, http://www.research.ibm.com/journal/rd/423/polastre.txt
Examiner	Date Considered
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	